

two lock chambers for carrying in and carrying out said substrates to be subjected to processing or said substrates which have been subjected to processing;

a single atmospheric transferring device for transferring, one by one, a substrate to be subjected to processing or a substrate which has been subjected to processing, between said cassette at said position and said two lock chambers; and

opening and closing devices provided respectively at a side of the cassette of said two lock chambers and being opened or closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, so as to change over said two lock chambers to being in an atmosphere or in a vacuum, wherein the method comprises the step of:

carrying in said substrate to be subjected to processing, or carrying out said substrate which has been subjected to processing, one by one, between the two lock chambers in the atmosphere and the cassette at said position, the opening and closing devices being opened and closed every carrying-in and carrying-out of said substrate, one by one.

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3. (Twice Amended) A method of transferring a substrate, using apparatus comprising:

a cassette table for mounting a cassette at a position of which an upper region of the position is open, a cassette transferring path, the cassette receiving plural substrates to be subjected to processing or plural substrates which have

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been subjected to processing;

a load lock chamber for carrying in said substrates to be subjected to processing;

an unload lock chamber for carrying out said substrates which have been subjected to processing;

a single atmospheric transferring device for transferring one by one a substrate to be subjected to processing or a substrate which has been subjected to processing, between said cassette at said position and said load lock chamber and said unload lock chamber; and

opening and closing devices provided respectively at a side of the cassette of said load lock chamber and said unload lock chamber and being opened or closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, so as to change over said load lock chamber and said unload lock chamber to be in an atmosphere or in a vacuum,

wherein the method comprises the step of:

carrying in said substrate to be subjected to processing, or carrying out said substrate which has been subjected to processing, one by one, between said load lock chamber and said unload lock chamber in the atmosphere and said cassette at said position, the opening and closing devices being opened and closed every carrying-in and carrying-out of said substrate, one by one.

8. (Amended) A method of transferring a substrate, comprising steps of:

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supplying a cassette, which receives plural substrates to be subjected to processing or plural substrates which have been subjected to processing, to a cassette table for mounting said cassette at a position of which an upper region of the position is open to a cassette transferring path;

C transferring a substrate to be subjected to processing or a substrate which has been subjected to processing between the cassette and at least one of two lock chambers which carry in and carry out said substrate to be subjected to processing or said substrate which has been subjected to processing, using a single atmospheric transferring device for transferring one by one between said cassette at said position and said at least one of two lock chambers; and

opening and closing using opening and closing devices which open or close respectively at a side of the cassette of said two lock chambers, the opening and closing devices being opened or closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, one by one, so as to change over said two lock chambers in an atmosphere or in a vacuum,


wherein between said two lock chambers in the atmosphere and said cassette at said position, said substrate to be subjected to processing or said substrate which has been subjected to processing is carried in or carried out one by one.

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9. (Amended) An apparatus for transferring a substrate, comprising:

a cassette table for mounting a cassette at a position of which an upper region of the position is open to a cassette transferring path, the cassette receiving plural substrates to be subjected to processing or plural substrates which have been subjected to processing;

two lock chambers for carrying in and carrying out said substrates to be subjected to processing or said substrates which have been subjected to processing;

 a single atmospheric transferring device for transferring one by one a substrate to be subjected to processing or a substrate which has been subjected to processing, between said cassette at said position and said two lock chambers; and

opening and closing devices provided respectively at a side of the cassette of said two lock chambers and being opened and closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, one by one, so as to change over said two lock chambers in an atmosphere or in a vacuum,

wherein between said two lock chambers in the atmosphere and said cassette at said position, said substrate to be subjected to processing or said substrate which has been subjected to processing is carried in or carried out one by one.

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11. (Amended) An apparatus for transferring a substrate, comprising:

a cassette table for mounting a cassette at a position of which an upper region of the position is open to a cassette transferring path, the cassette receiving plural substrates to be subjected to processing or plural substrates which have been subjected to processing;

a load lock chamber for carrying in said substrates to be subjected to processing;

an unload lock chamber for carrying out said substrates which have been subjected to processing;

C a single atmospheric transferring device for transferring one by one a substrate to be subjected to processing or a substrate which has been subjected to processing, between said cassette at said position and said load lock chamber and said unload lock chamber; and

opening and closing devices provided respectively at a side of the cassette of said load lock chamber and said unload lock chamber and being opened and closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, one by one, so as to change over said load lock chamber and said unload lock chamber in an atmosphere or in a vacuum,

wherein between said load lock chamber and said unload lock chamber in the atmosphere and said cassette at said position, said substrate to be subjected to processing or said substrate which has been subjected to processing is carried in

*Ch* or carried out one by one.

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